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Customer No. 22,852
Attorney Docket No. 04329.2620

jc872 U.S. PTO
09/923443
08/08/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Hiroshi NOMURA et al)
Serial No.: Not Yet Assigned) Group Art Unit:
Filed: August 8, 2001) Examiner:
For: EVALUATION MASK, FOCUS)
MEASURING METHOD AND)
ABERRATION MEASURING)
METHOD)

Assistant Commissioner for Patents
Washington, DC 20231

Sir: **INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the documents listed on attached Form PTO-1449. Copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-referenced application,

LAW OFFICES
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& DUNNER, L.L.P.
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202-408-4000

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

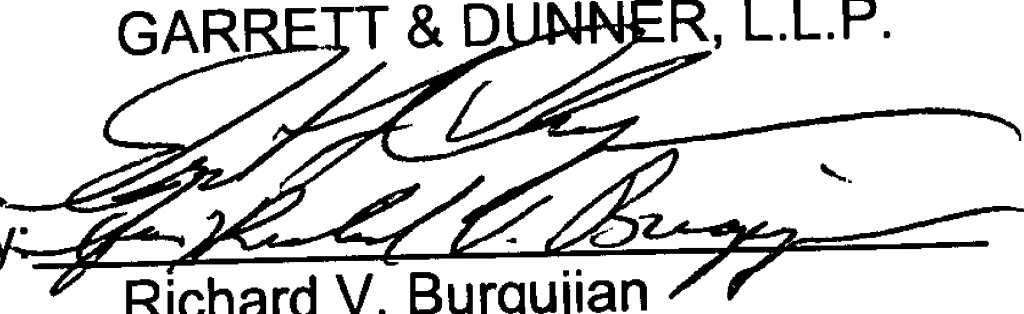
If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: August 8, 2001

By:


Richard V. Burgujian
Reg. No. 31,744

Enclosures
EFC/FPD/bl

ERNEST F. CHAPMAN
Reg. No. 25,961

INFORMATION DISCLOSURE CITATION

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|------------------|---------------------------------|------------|--|
| Atty. Docket No. | 04329.26220 | Serial No. | |
| Applicant | Hiroshi NOMURA and Kenji KONOMI | | |
| Filing Date | August 8, 2001 | Group: | |

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| U.S. PATENT DOCUMENTS | | | | | | | |
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| | | Document Number | Publication Date | Country | Class | Sub Class | Translation Yes or No |
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| | J.P. Kirk et al., "APPLICATION OF BLAZED GRATINGS FOR DETERMINATION OF EQUIVALENT PRIMARY AZIMUTHAL ABERRATIONS", Optical Microlithography XII, Luc Van den Hove ed., Proc. SPIE. Vol. 3679, 70-76 (1999) |
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